

300mm Semi-Automatic Vacuum Mounter

RAD-2512m/12



Outline

- Semi-automatic vacuum mounter that can mount a wafer to a pre-cut dicing tape mounted on a ring frame. This process is performed under a vacuum atmosphere.
- By using our unique vacuum control method, wafer mounting is performed without any contact to the wafer surface.
- By using our unique differential pressure control mechanism, excellent conformity to stepped surfaces is achieved.

Options

• Heater Table

Suitable Tape

• Dicing Tape: Adwill D Series, G Series

Facility

Power Supply	Voltage	: AC200-230V±10% (AC190-253V)
	Frequency	: 50/60Hz
	Phase	: Single phase
Air Supply	Power consumption	: 15kW
	Air pressure	: 0.6-0.8MPa
	Air consumption	: <100L/min (ANR)
Vacuum Supply (for vacuum chamber)	Ultimate Pressure	: 1.0Pa
	Pumping Speed	: >250L/min

Applicable Wafer Size

150mm, 200mm, 300mm(Warpage: >2mm)

Size

Width(W) : 1,100mm
Depth(D) : 660mm(excluding protruding parts)
Height(H) : 1,098mm
(When upper chamber is fully open)

Weight

400kg

UPH

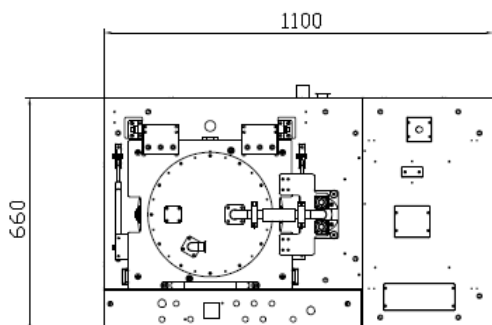
60sec/wafer (excludes setting time)

The above processing capacity is based on following conditions:

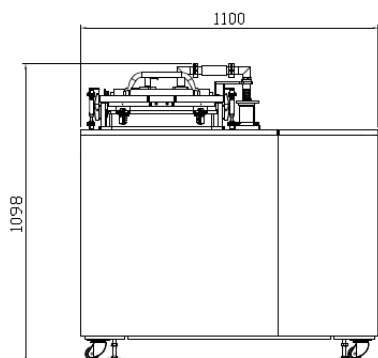
Wafer : 200mm non-polished mirror wafer

External View

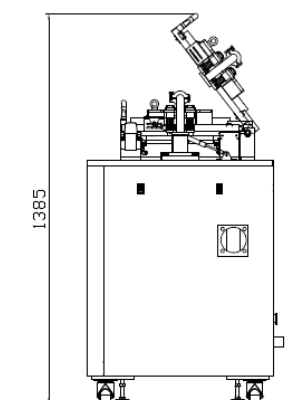
Unit:mm



Top View



Front View



Right Side View



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